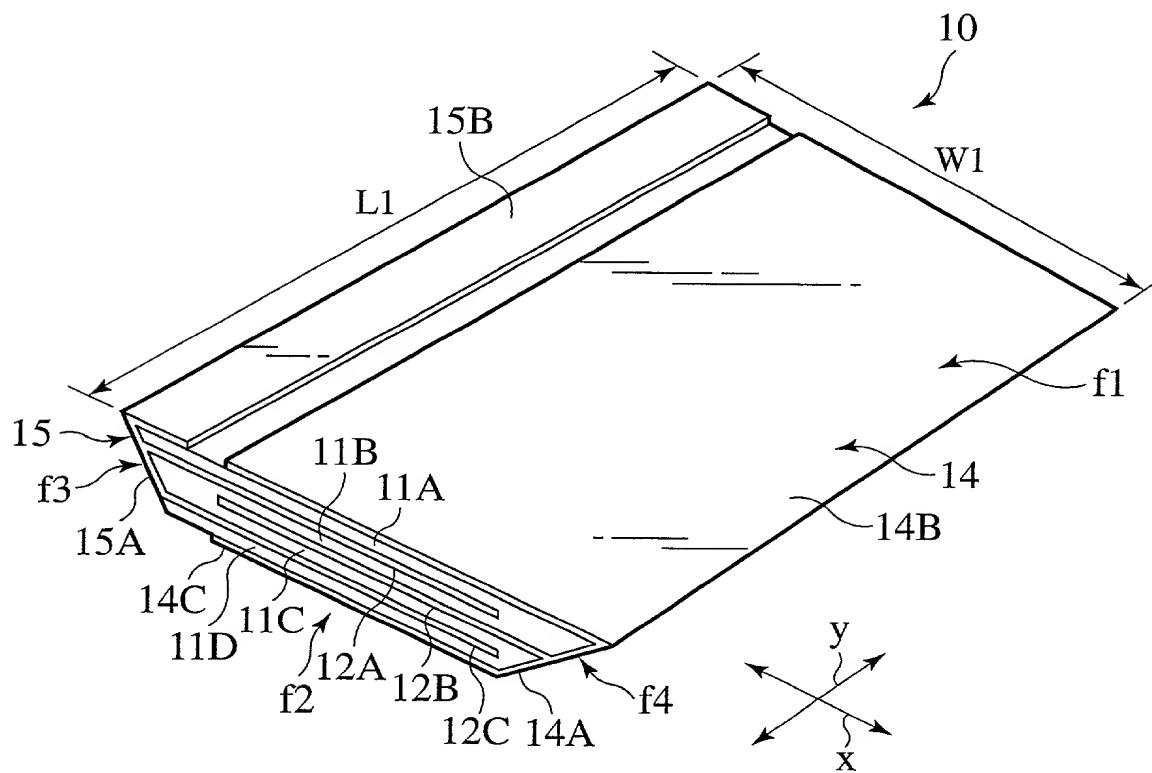


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FIG.1



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FIG.2

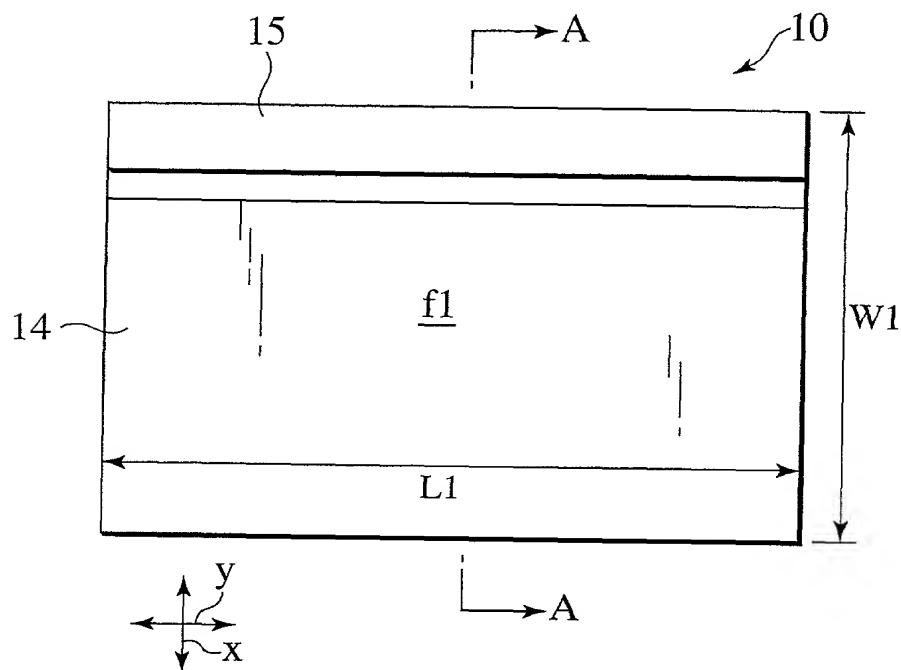
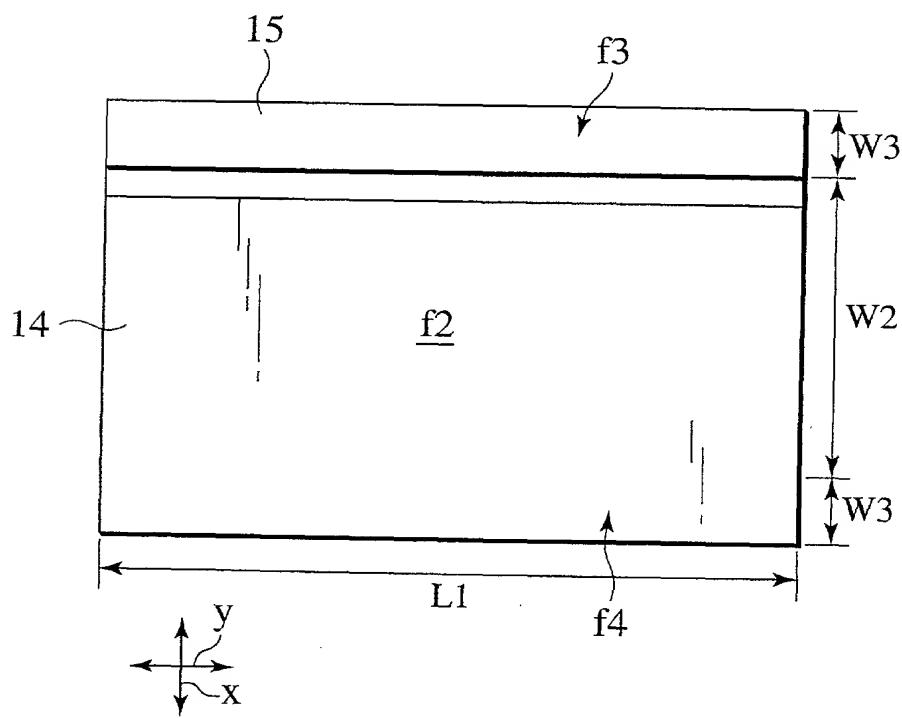
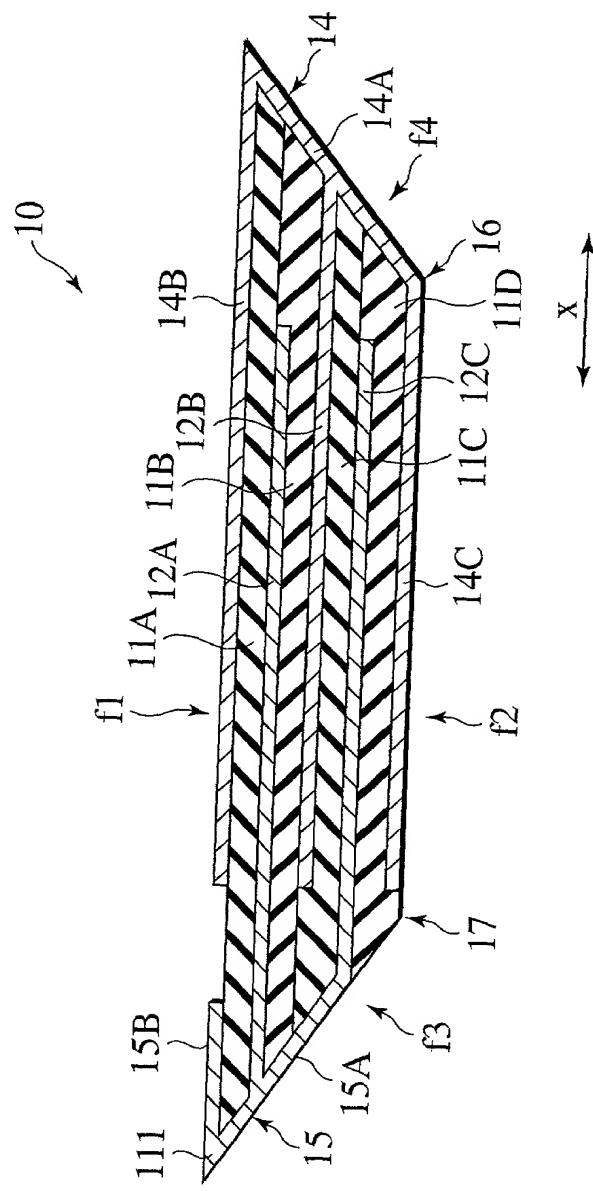


FIG.3



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FIG.4



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FIG.5

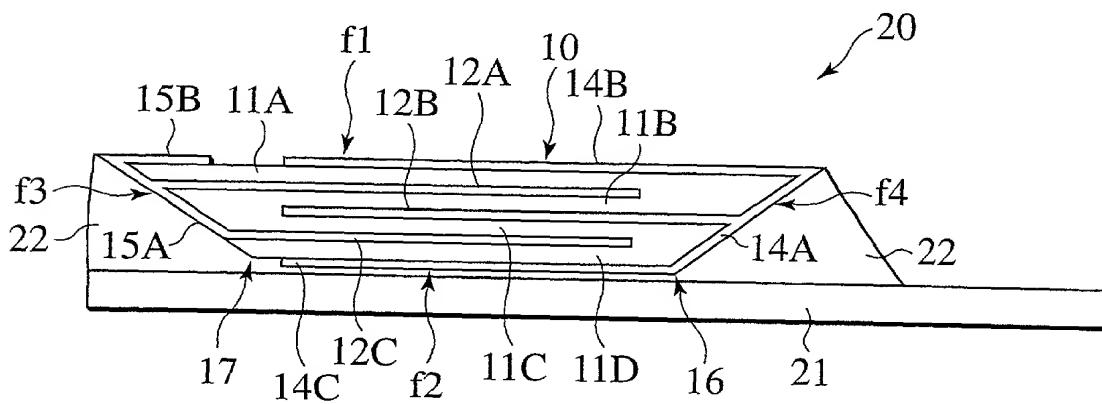
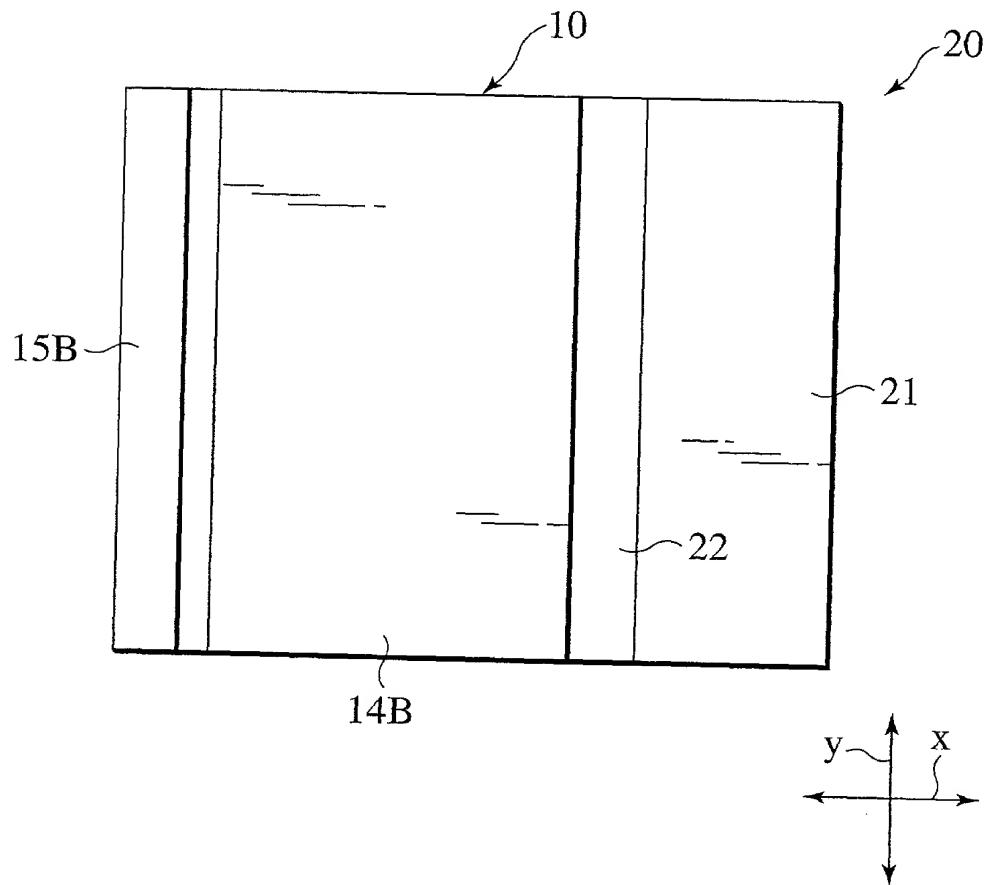


FIG.6



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FIG.7

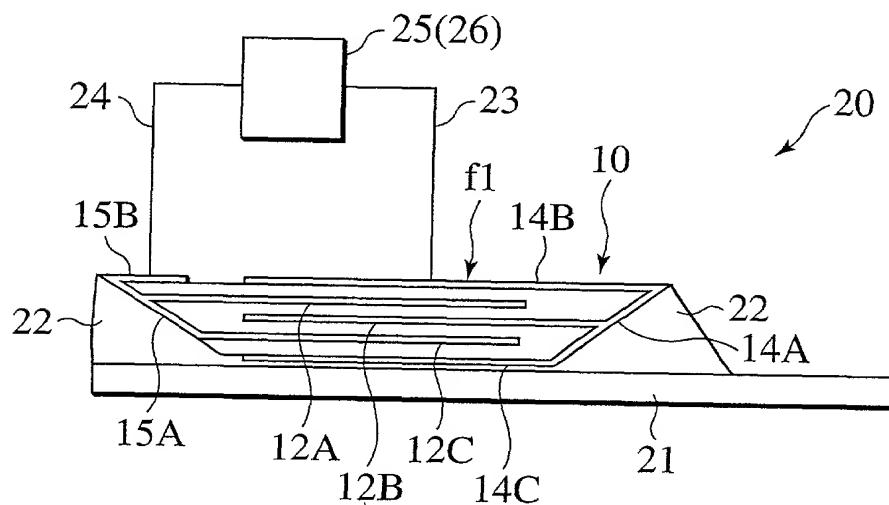
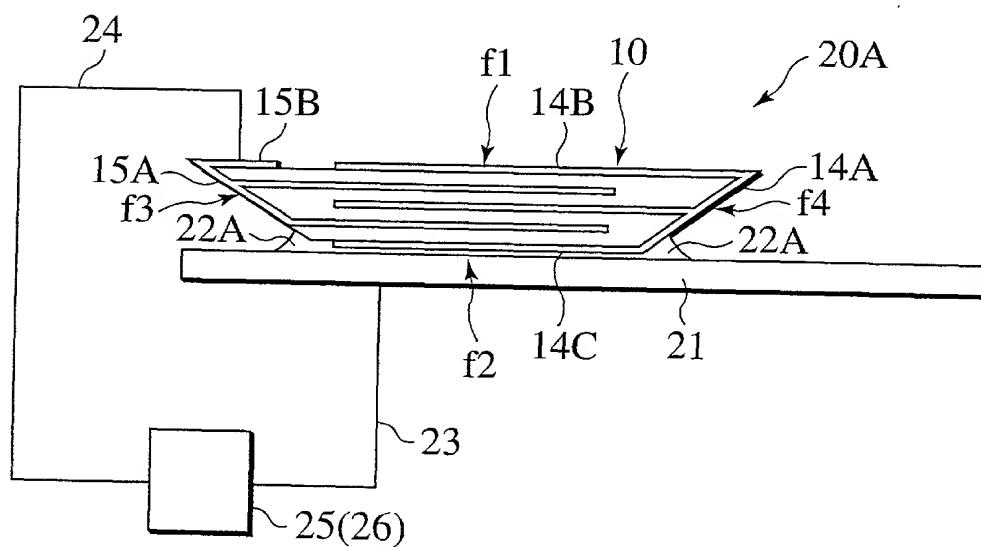
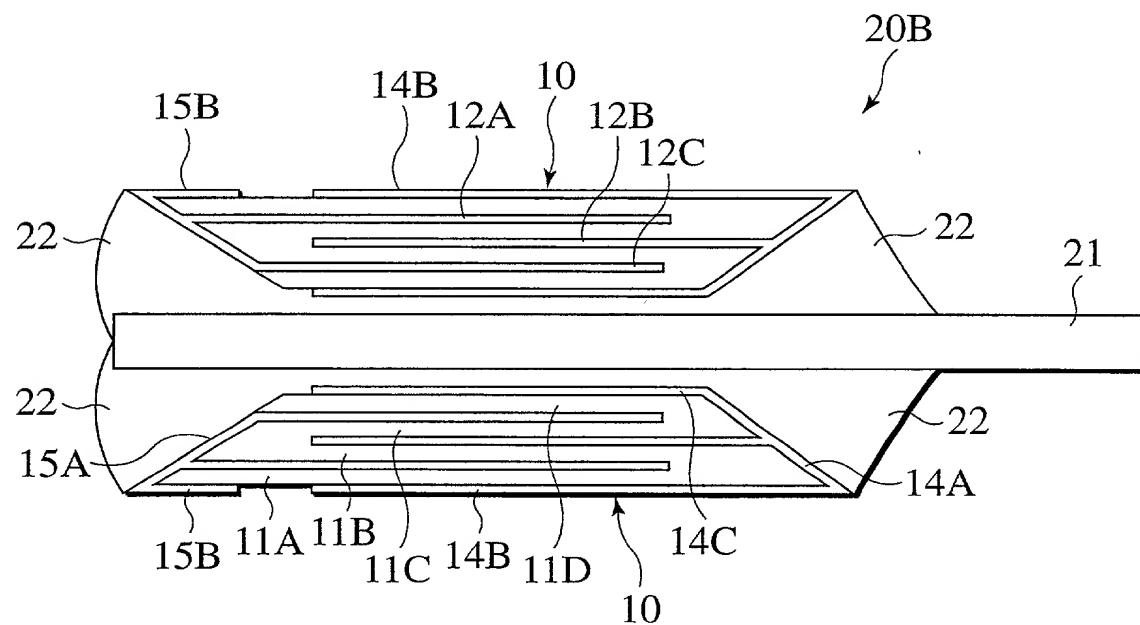


FIG.8



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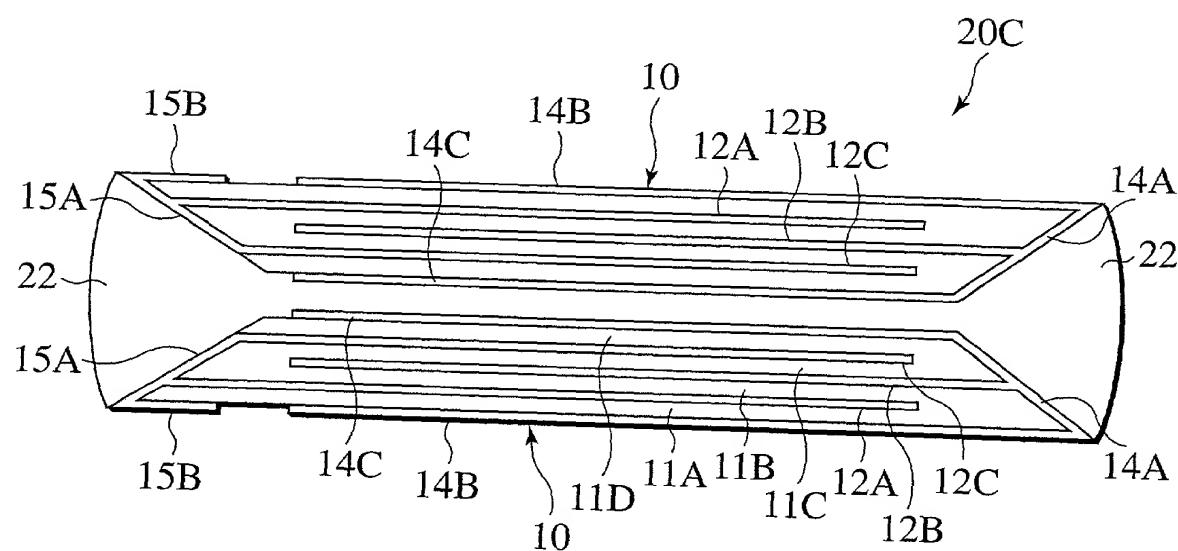
FIG.9



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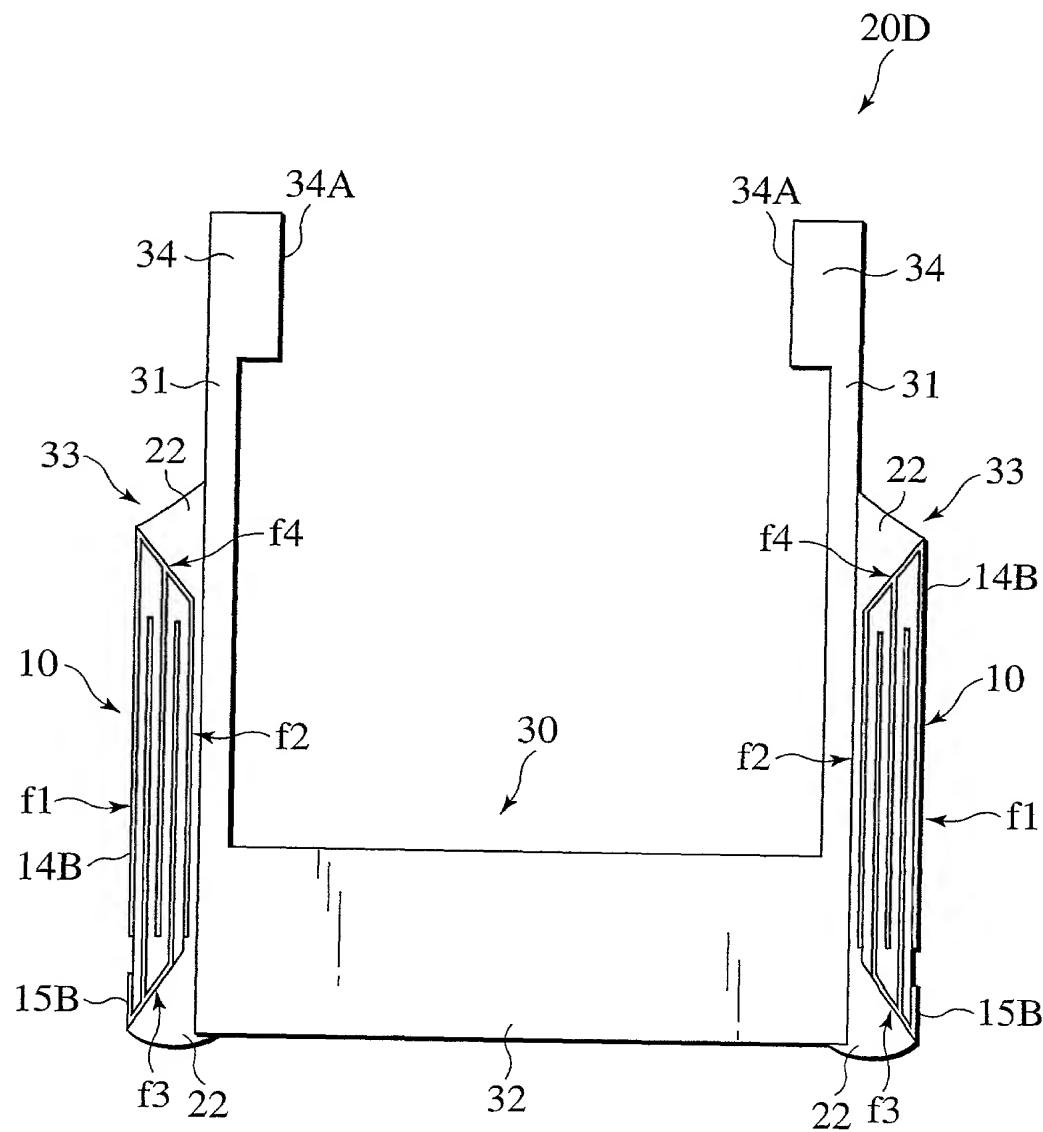
FIG.10

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FIG.11



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FIG.12

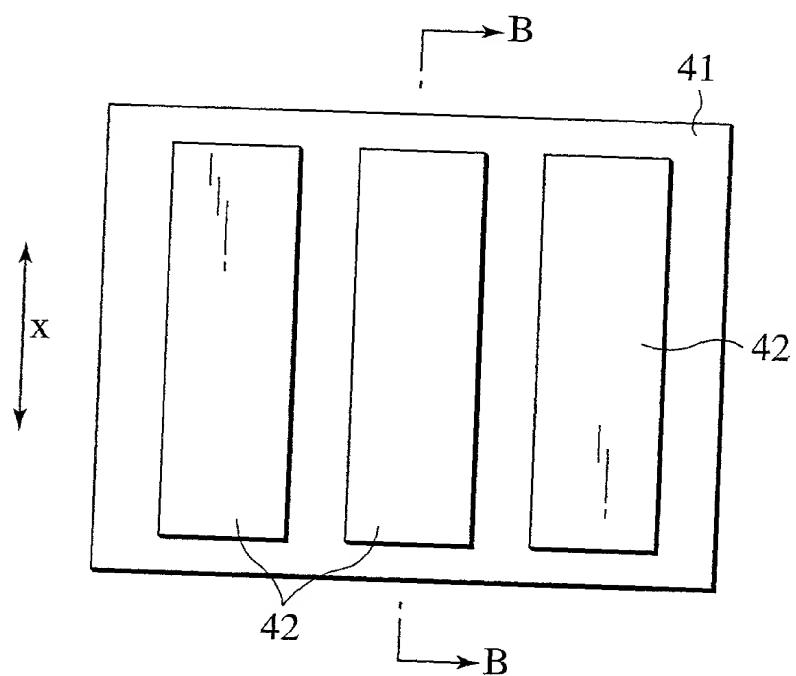
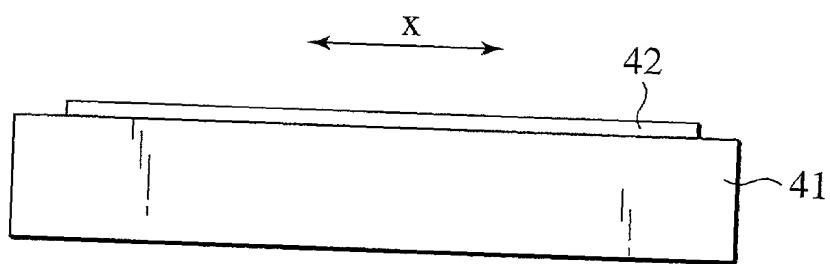


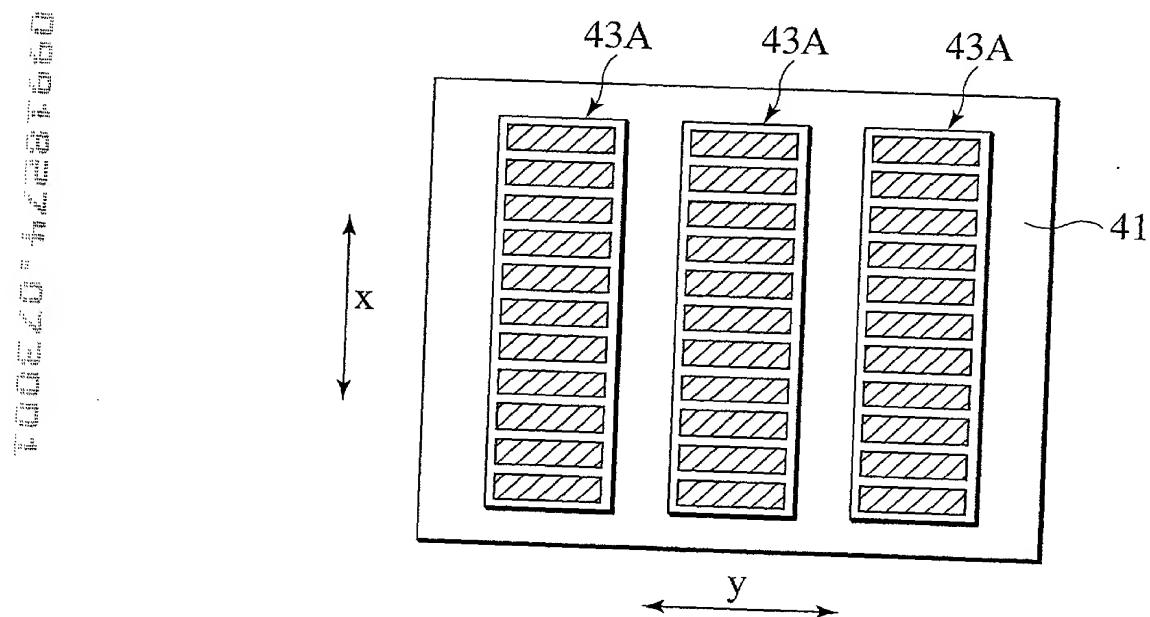
FIG.13



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FIG.14



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FIG.15

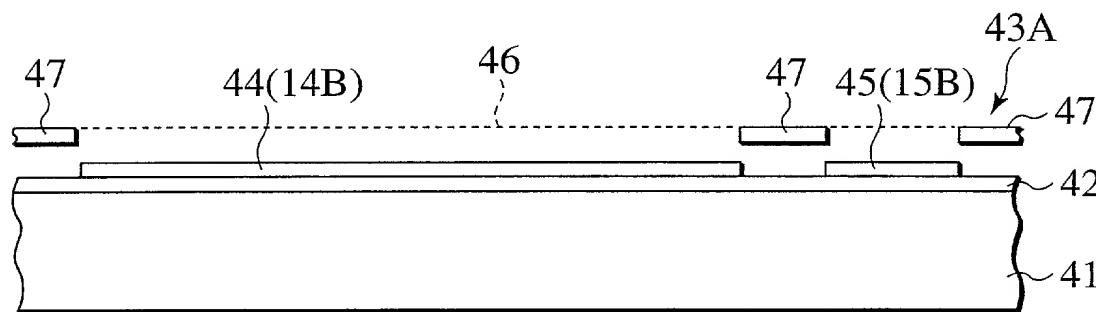
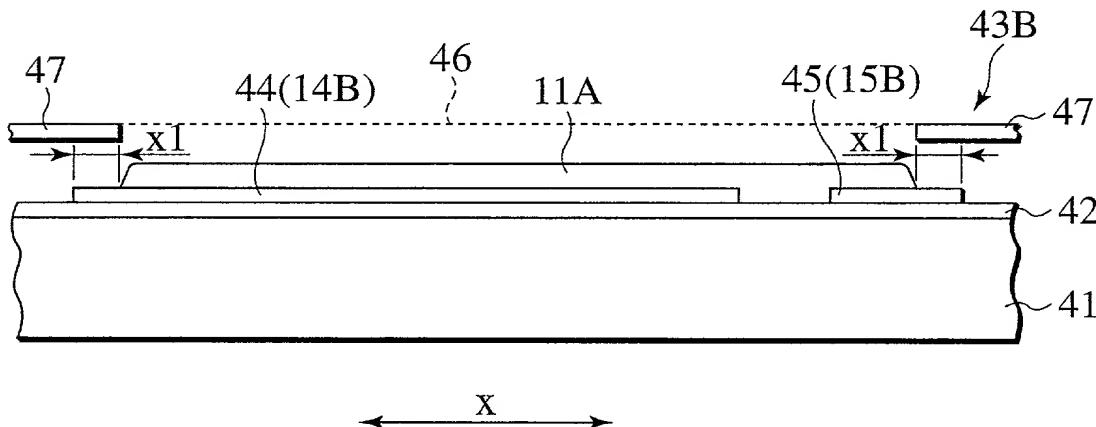


FIG.16



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FIG.17

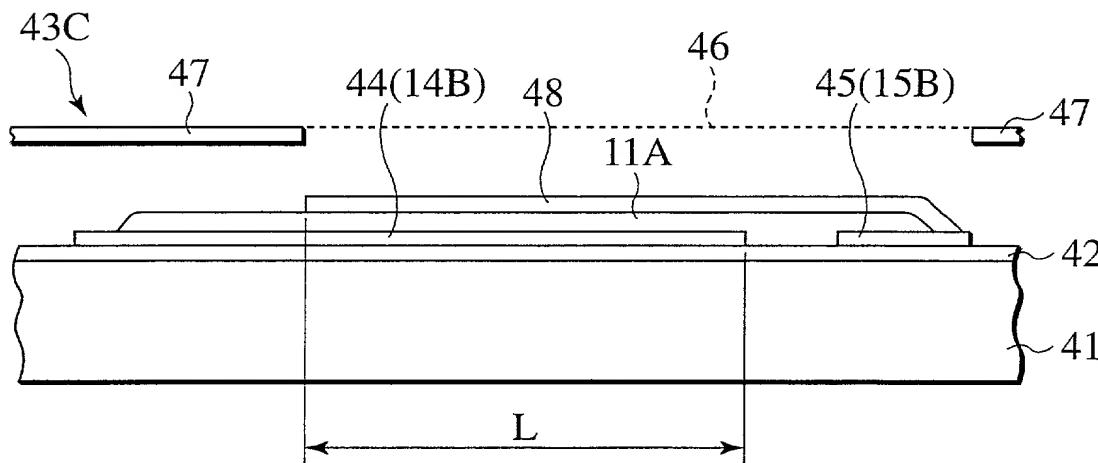
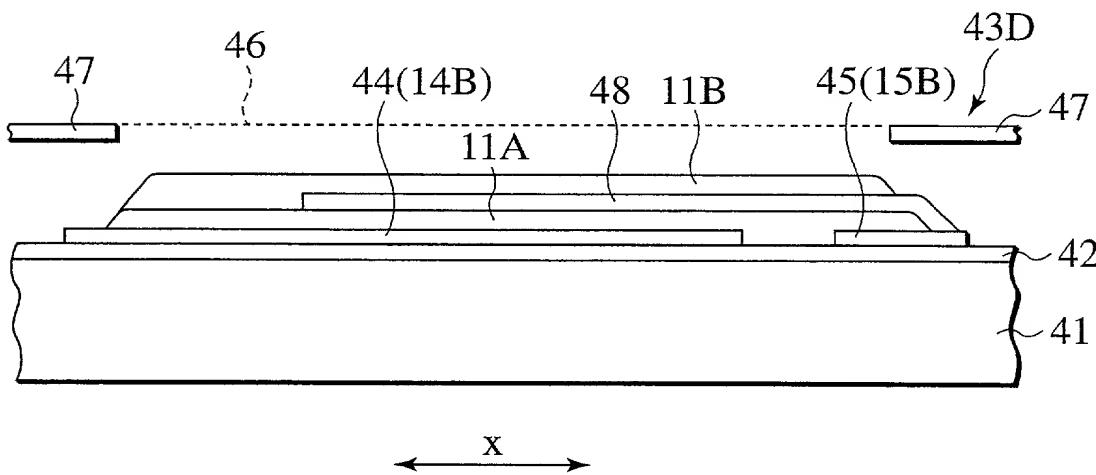


FIG.18



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FIG.19

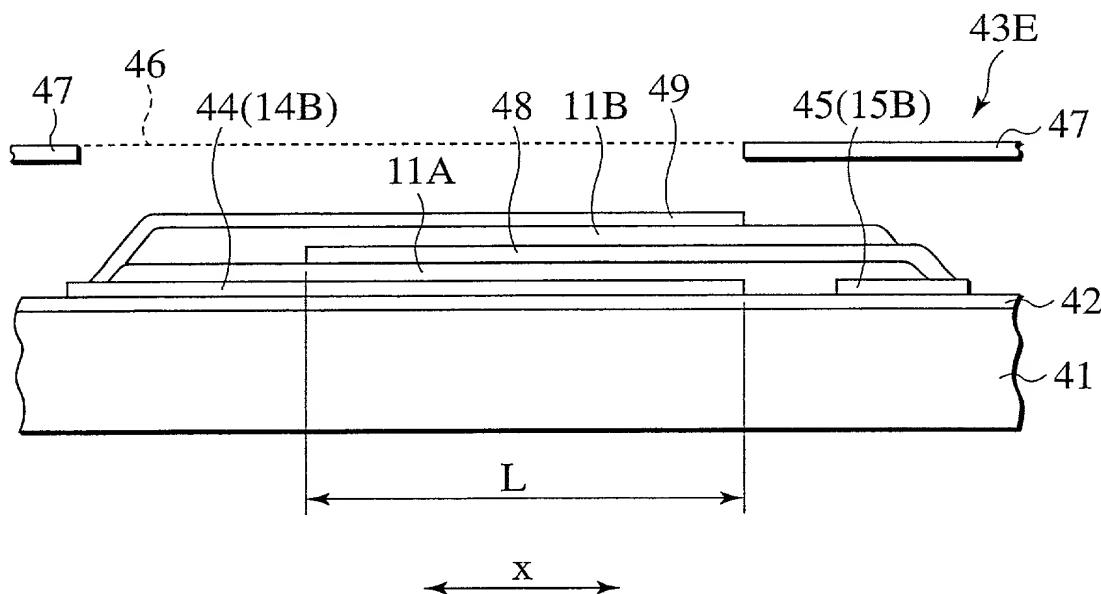
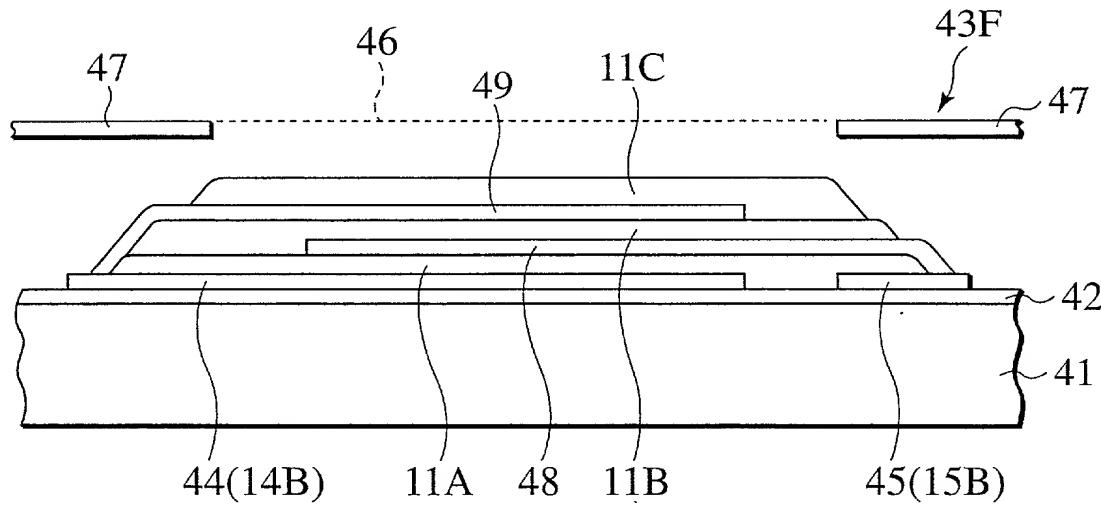


FIG.20



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FIG.21

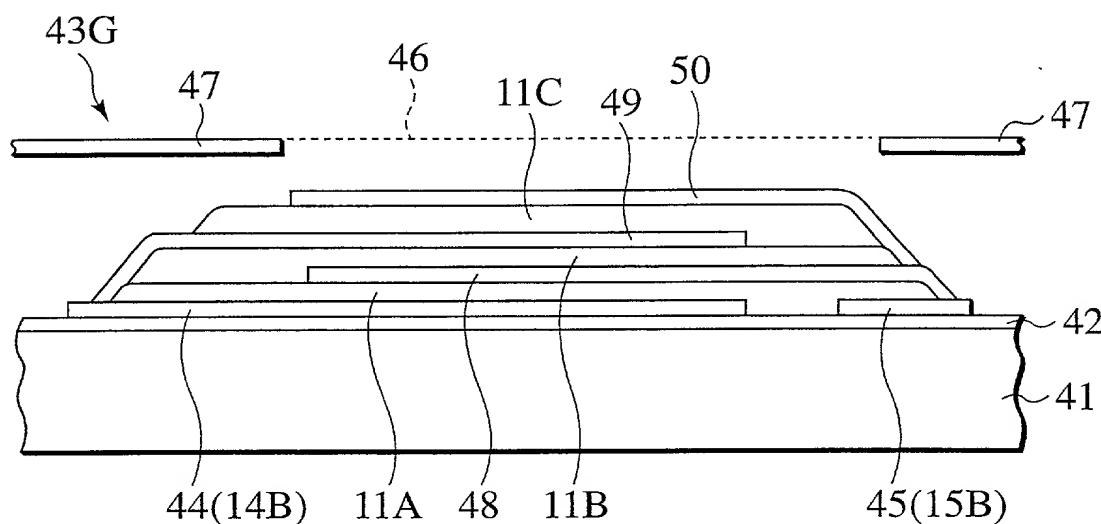
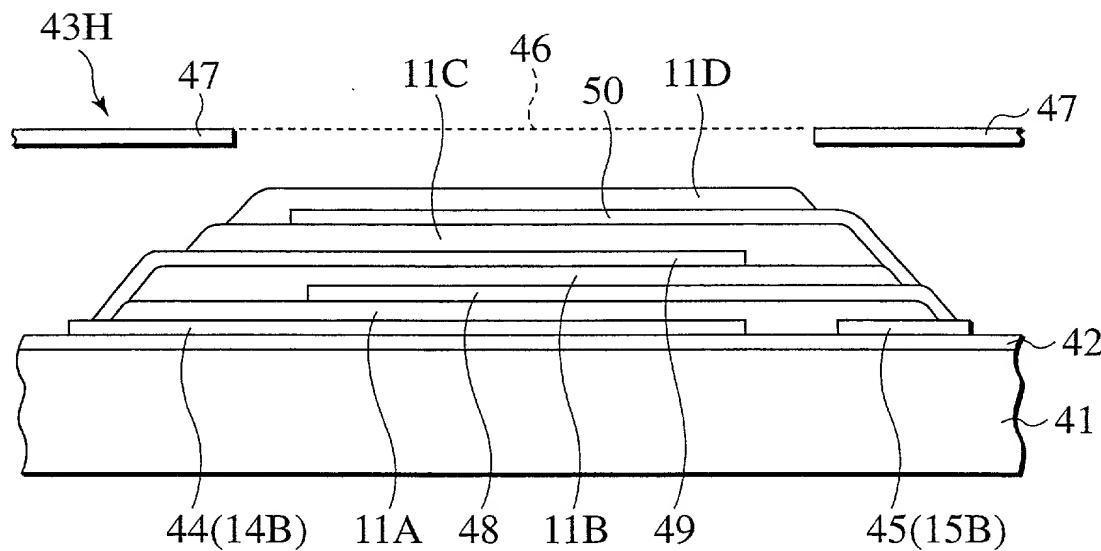


FIG.22



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FIG.23

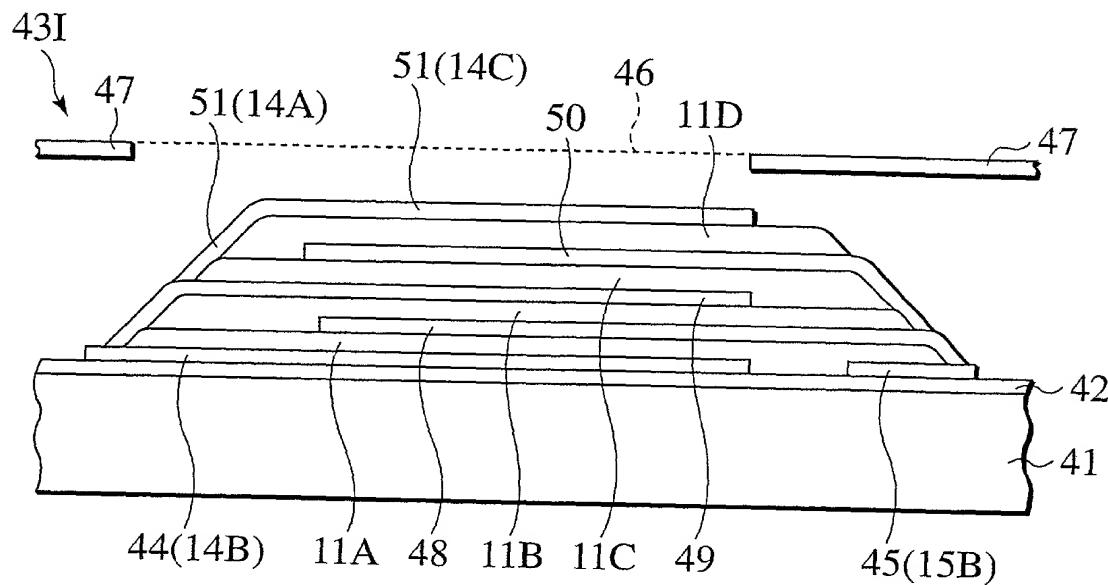
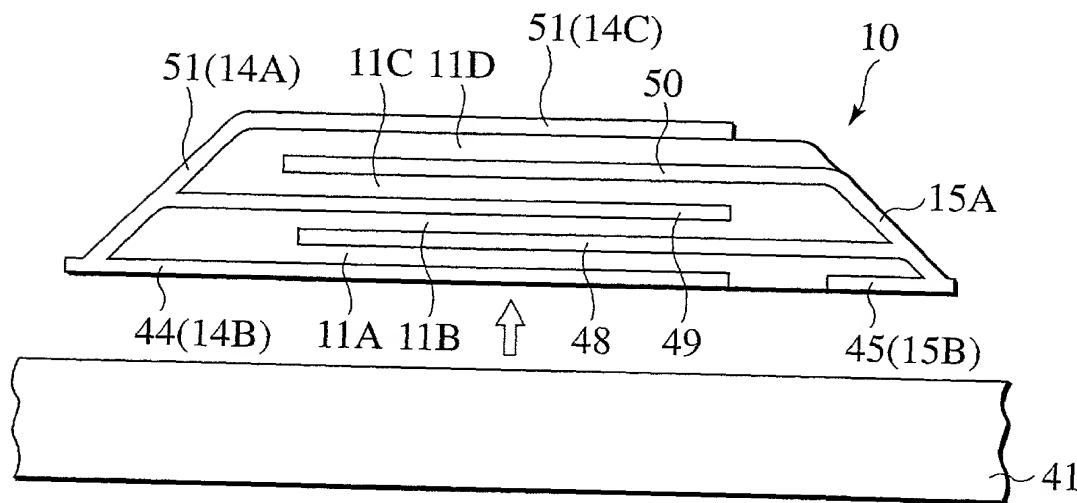


FIG.24



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FIG.25

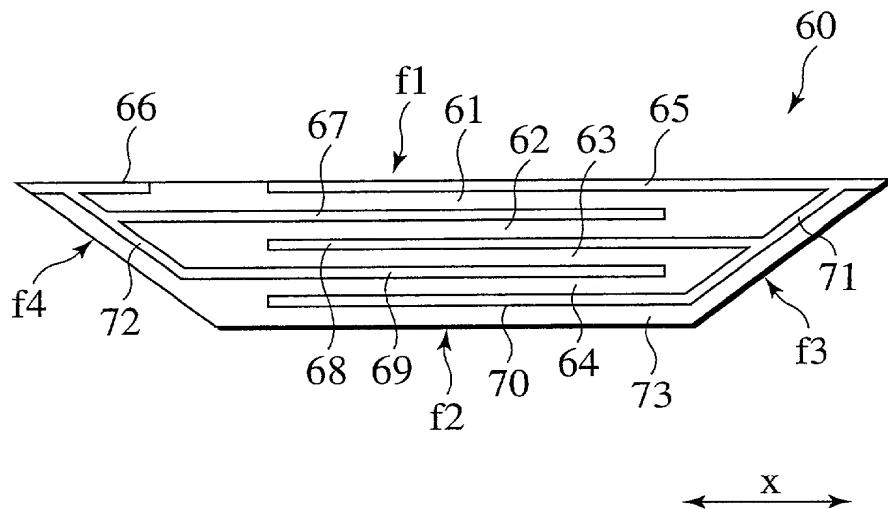
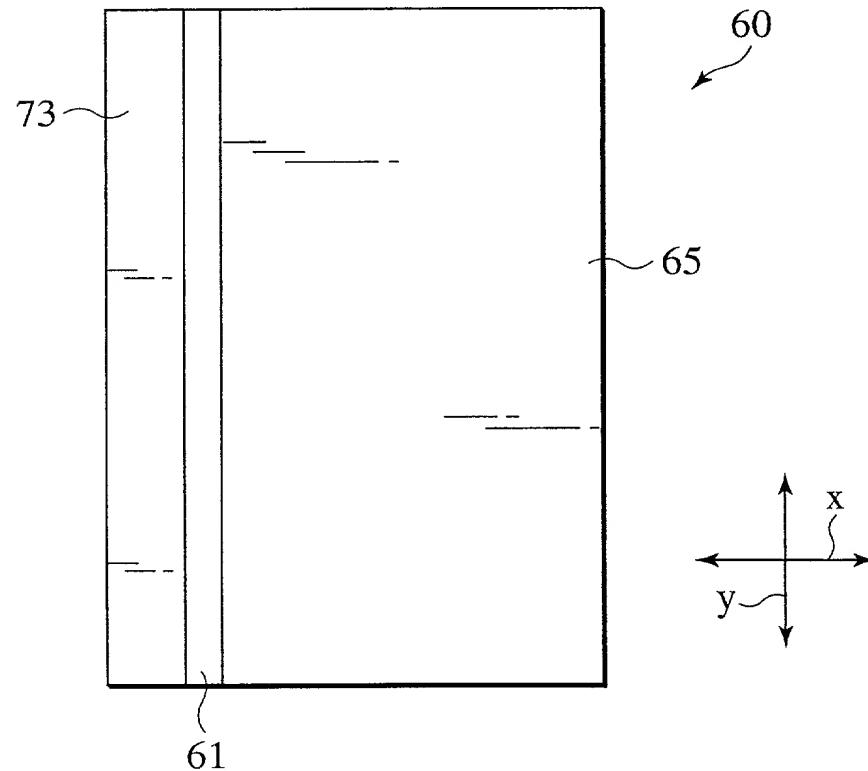
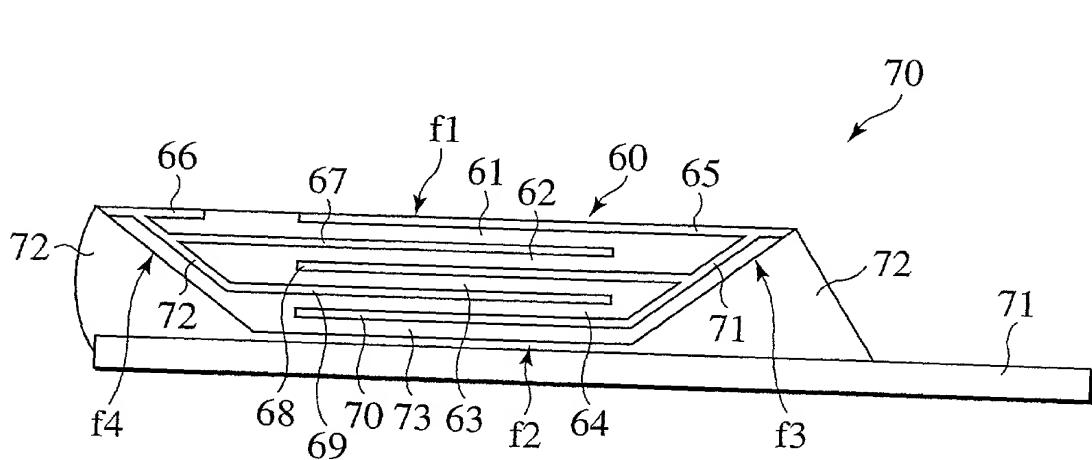


FIG.26



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FIG.27



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FIG.28

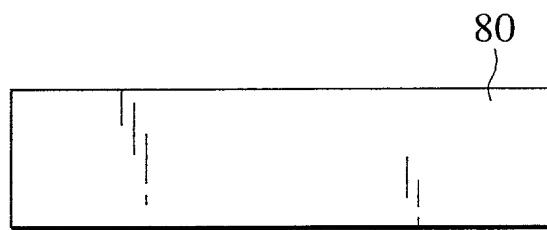
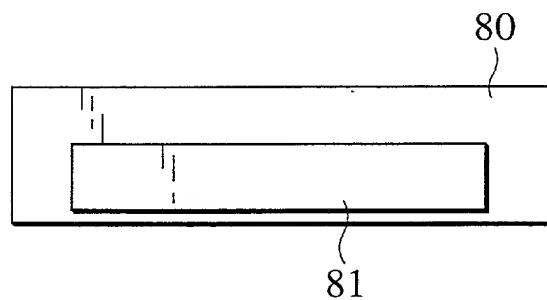
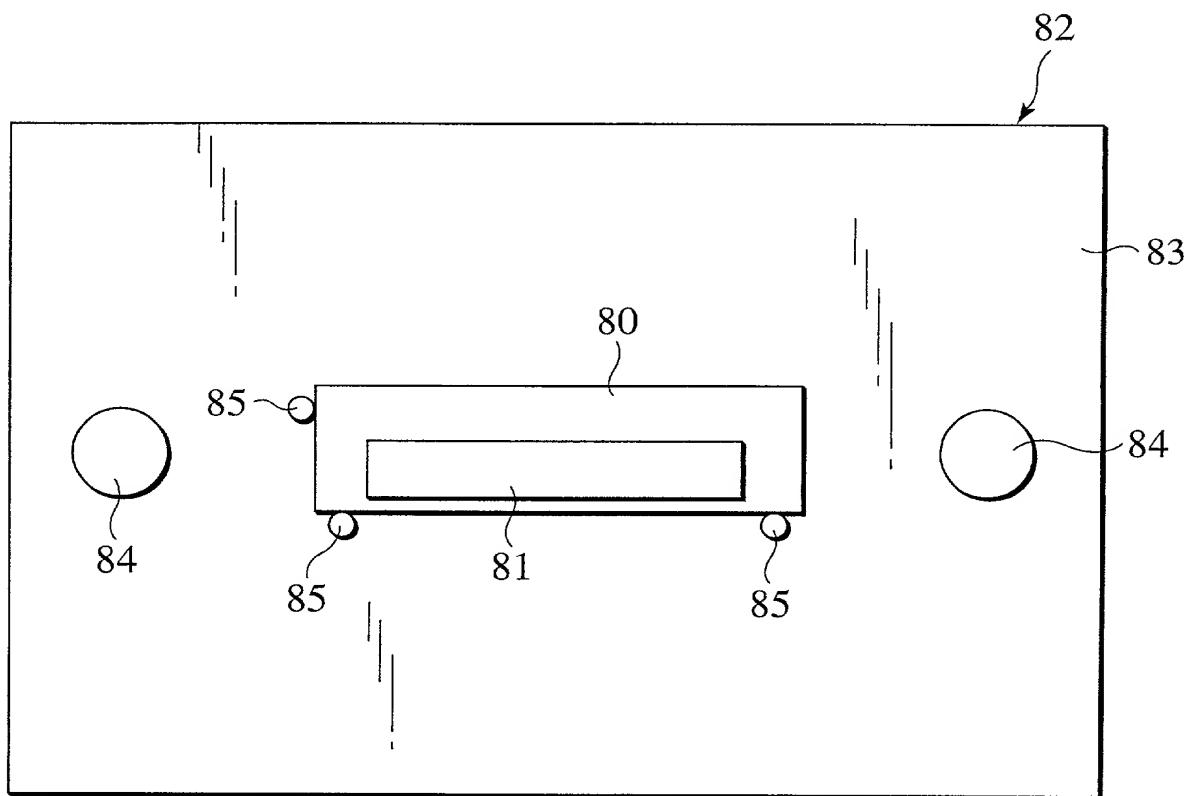


FIG.29



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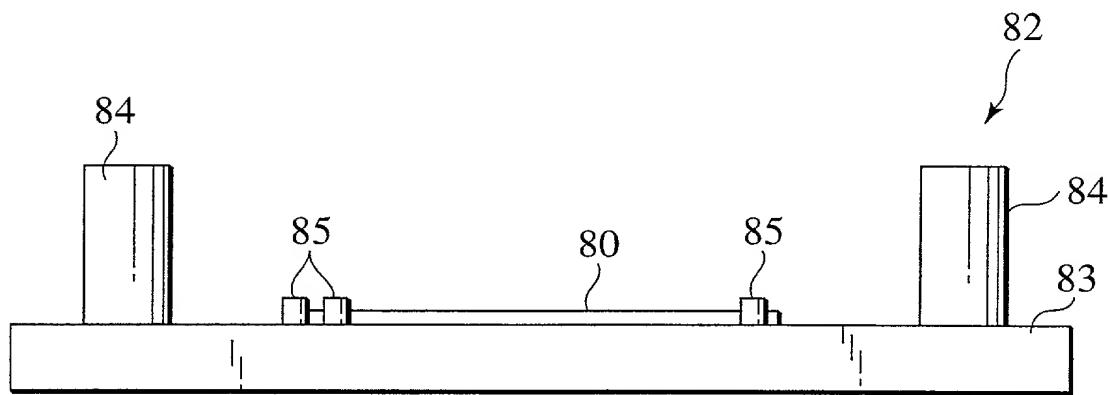
FIG.30



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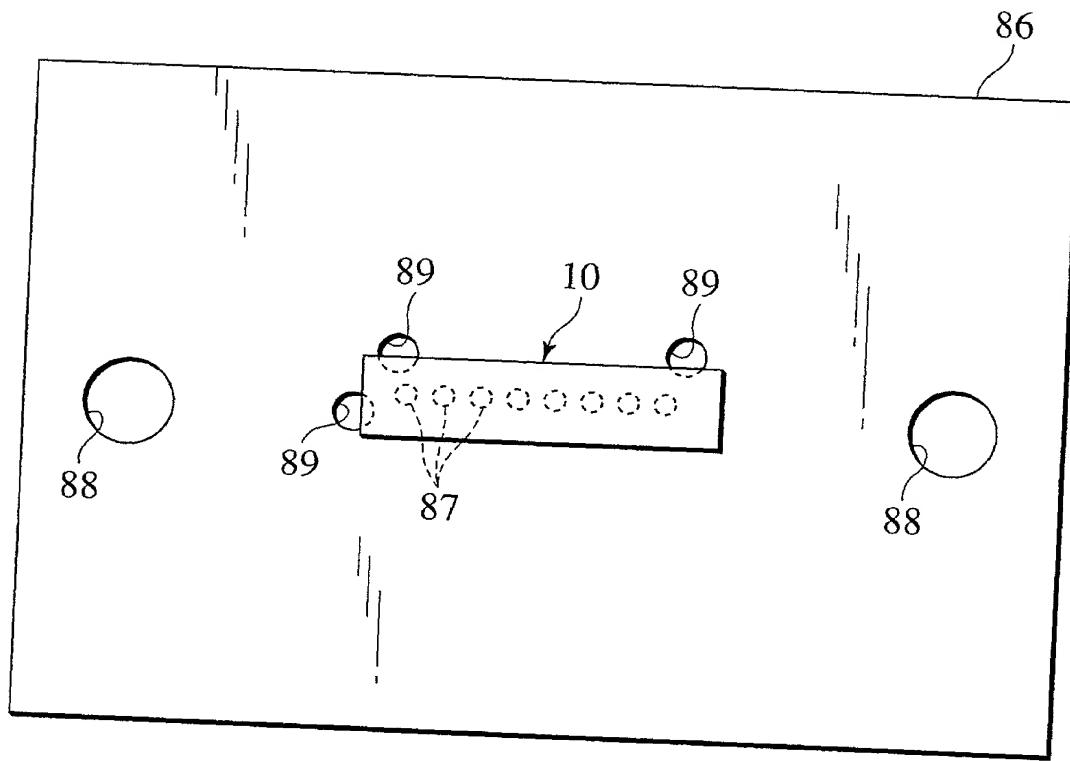
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FIG.31



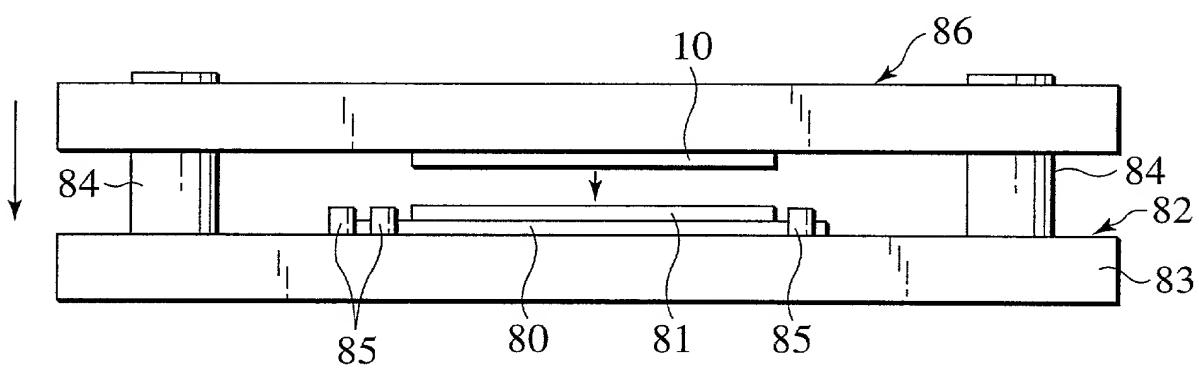
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FIG.32



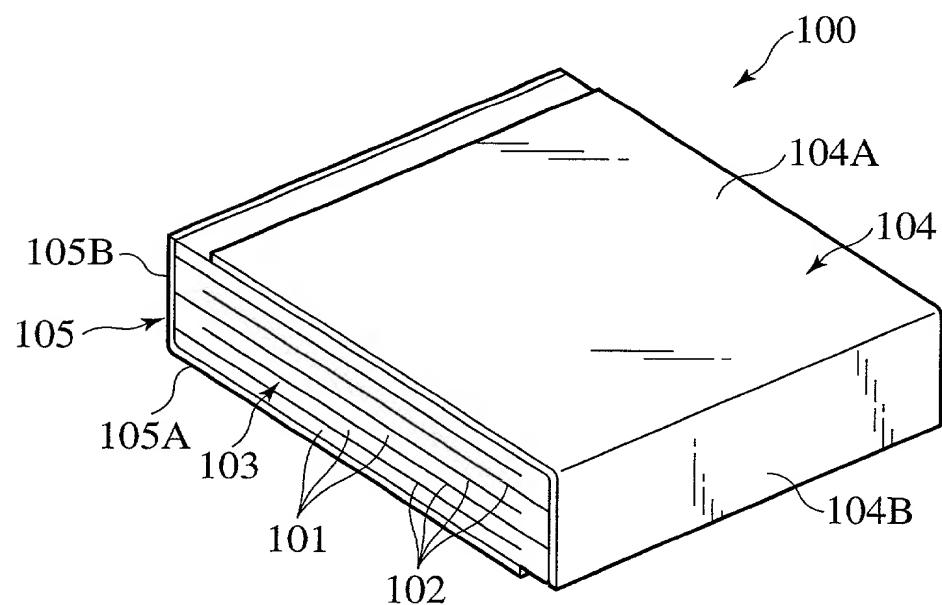
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FIG.33



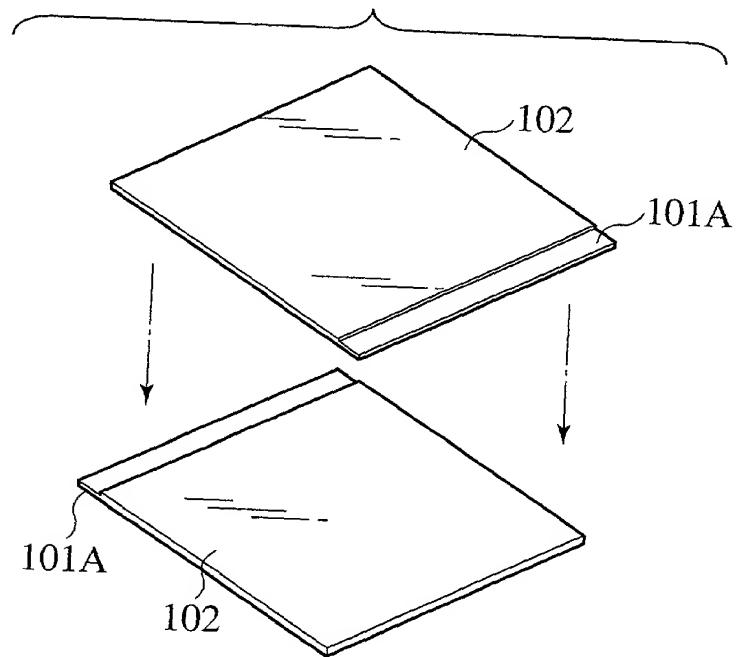
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FIG.34



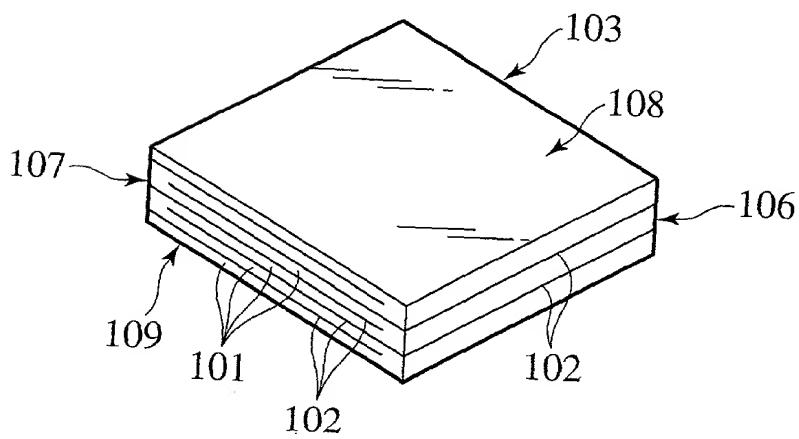
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FIG.35



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FIG.36



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FIG.37

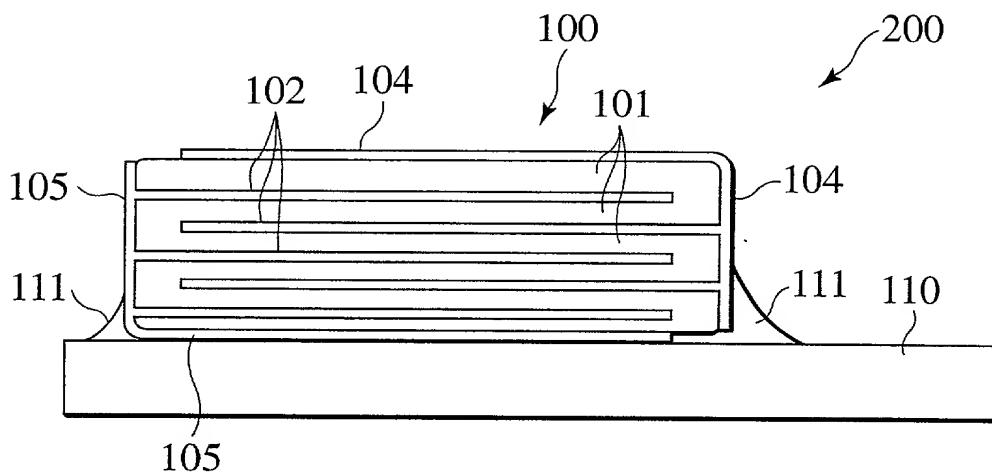
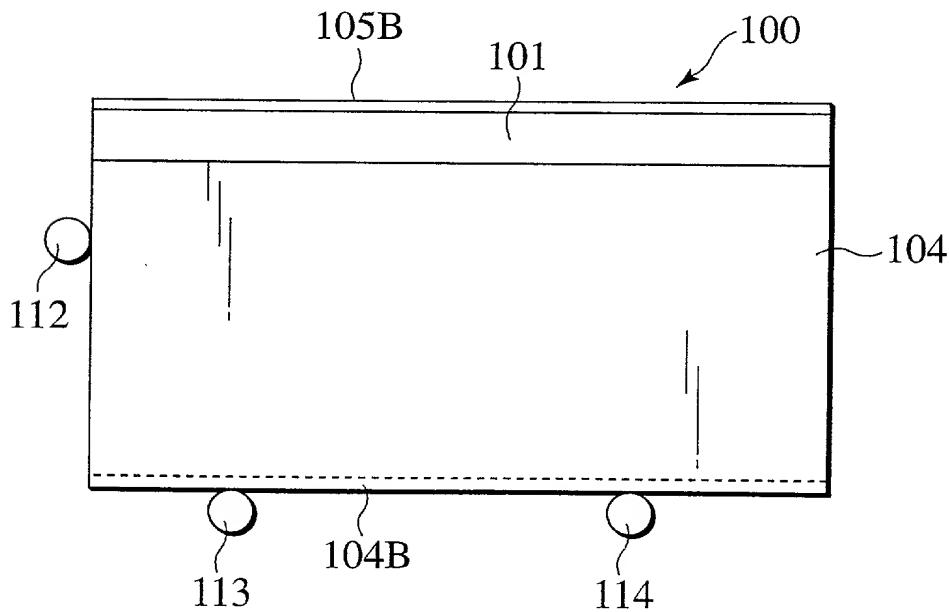


FIG.38



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FIG.39

